

(FW)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: W. SCHWARZENBACH et al. Confirmation No.: 9739  
Application No.: 10/733,729 Group Art Unit: 2818  
Filing Date: December 12, 2003 Examiner: David Nhu  
For: METHOD OF MAKING CAVITIES IN A Semiconductor Attorney Docket No.: 4717-9200  
SEMICONDUCTOR

**REQUEST FOR CORRECTION OF FILING RECEIPT**

Office of Initial Patent Examination  
Customer Service Center  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

A Filing Receipt for the above-identified application has been received and the following corrections are respectfully requested.

Please change the spelling of the city address of applicant Christophe Maleville from "La Terasse" to -- La Terrasse --.


Please change the foreign application number from "0216049" to -- 0216409 --. In support of this change, see the certified priority document filed May 7, 2004.

A marked-up copy of the Filing Receipt with the requested changes noted thereon is attached. Please issue a corrected Filing Receipt in due course.

No fee is believed to be due for this submission. Should any fees be required, however, please charge such fees to Winston & Strawn LLP Deposit Account No. 50-1814.

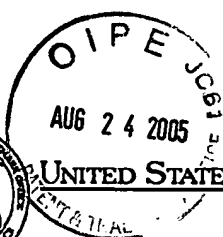
Respectfully submitted,

Aug. 24, 2005  
Date

  
E. Bradley Gould (Reg. No. 41,792)  
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WINSTON & STRAWN LLP  
Customer No. 28765

202-282-5771



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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/733,729	12/12/2003	2812	1094	4717-9200	3	26	4

CONFIRMATION NO. 9739

28765  
 WINSTON & STRAWN  
 PATENT DEPARTMENT  
 1400 L STREET, N.W.  
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UPDATED FILING RECEIPT



\*OC000000012920646\*

Date Mailed: 06/10/2004

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

## Applicant(s)

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La Terrasse

## Domestic Priority data as claimed by applicant

This appln claims benefit of 60/448,124 02/20/2003

## Foreign Applications

FRANCE 0216049 12/20/2002

0216409

If Required, Foreign Filing License Granted: 03/17/2004

Projected Publication Date: 09/16/2004

Non-Publication Request: No

Early Publication Request: No

## Title

Method of making cavities in a semiconductor wafer